

Ultralow voltage operation and microwatt power consumption MXene based pressure sensors with excellent sensing performance

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Figure S1 Digital image of the MXene/PDMS composites.

Figure S2 Digital image of the Au interdigital electrode on PET substrate, the electrode composes of Cu/Ni/Au three layers from bottom to the top.

Figure S3 I-V curve of MXene/PDMS piezoresistive sensor without pressure applied.

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Figure S5 Resistance change curve of MXene/PDMS piezoresistive sensor under continuous pressure applied from 0 to 436 kPa.

Figure S6 Response curve of MXene/PDMS piezoresistive sensor.

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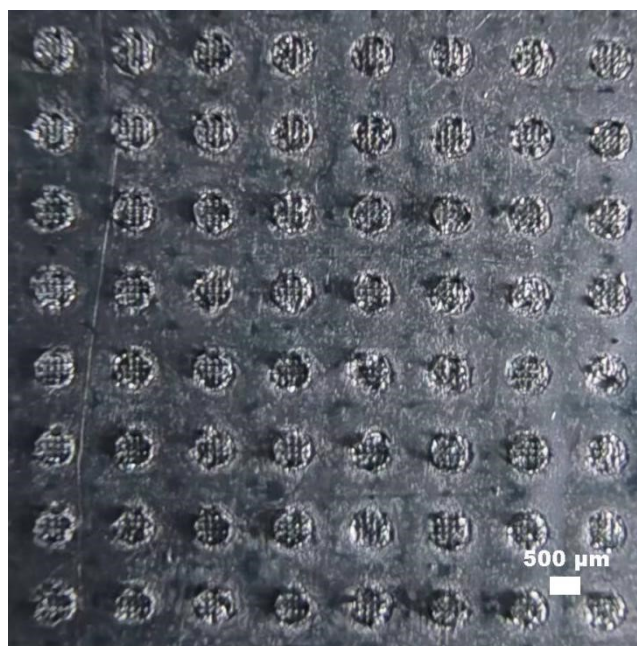


Figure S1 Digital image of the MXene/PDMS composites.

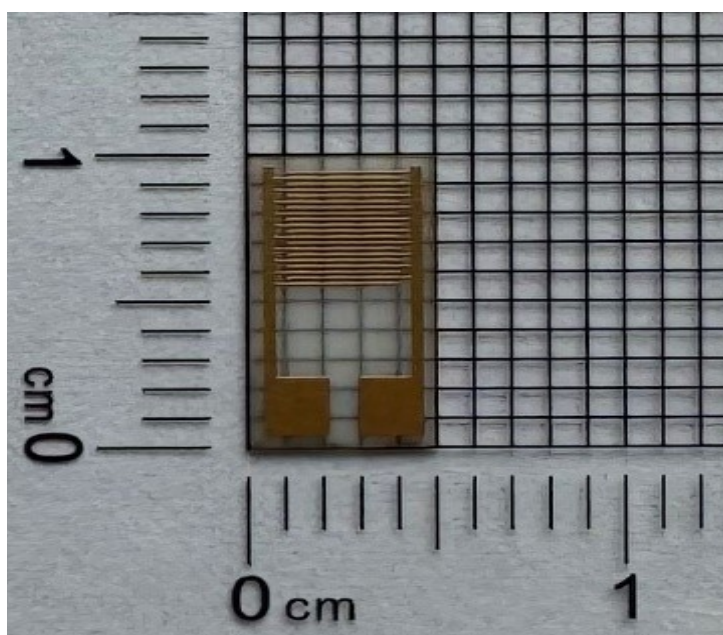


Figure S2 Digital image of the Au interdigital electrode on PET substrate, the electrode composes of Cu/Ni/Au three layers from bottom to the top.

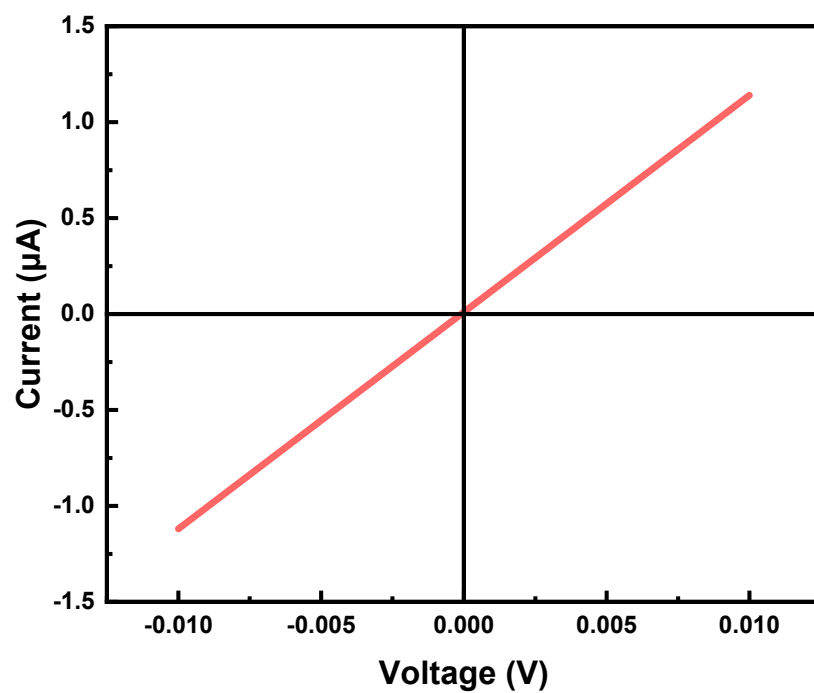


Figure S3 I-V curve of MXene/PDMS piezoresistive sensor without pressure applied.

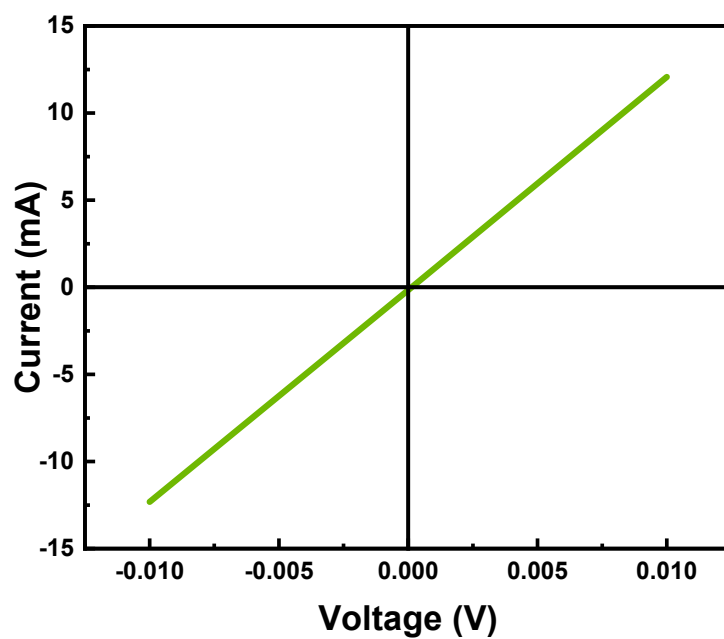


Figure S4 I-V curve of MXene/PDMS piezoresistive sensor under the pressure of 436 kPa.

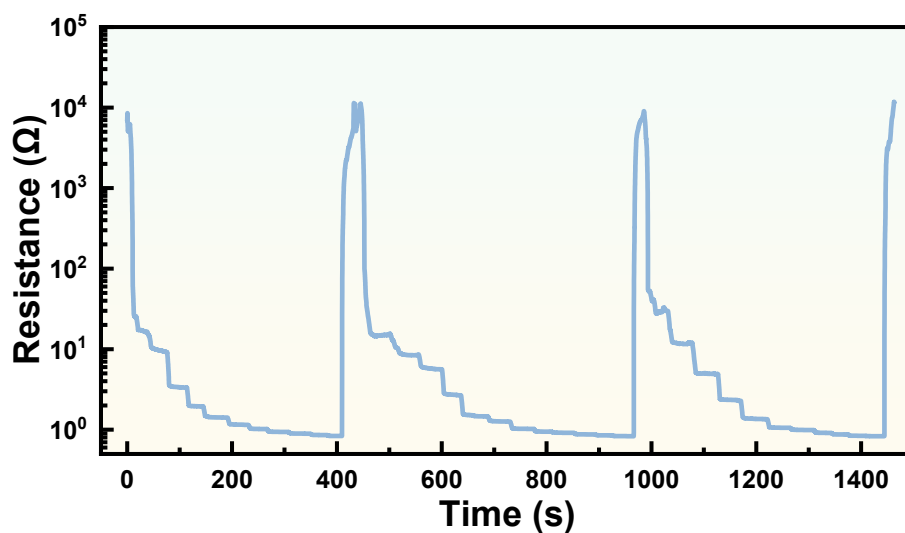


Figure S5 Resistance change curve of MXene/PDMS piezoresistive sensor under continuous pressure applied from 0 to 436 kPa.

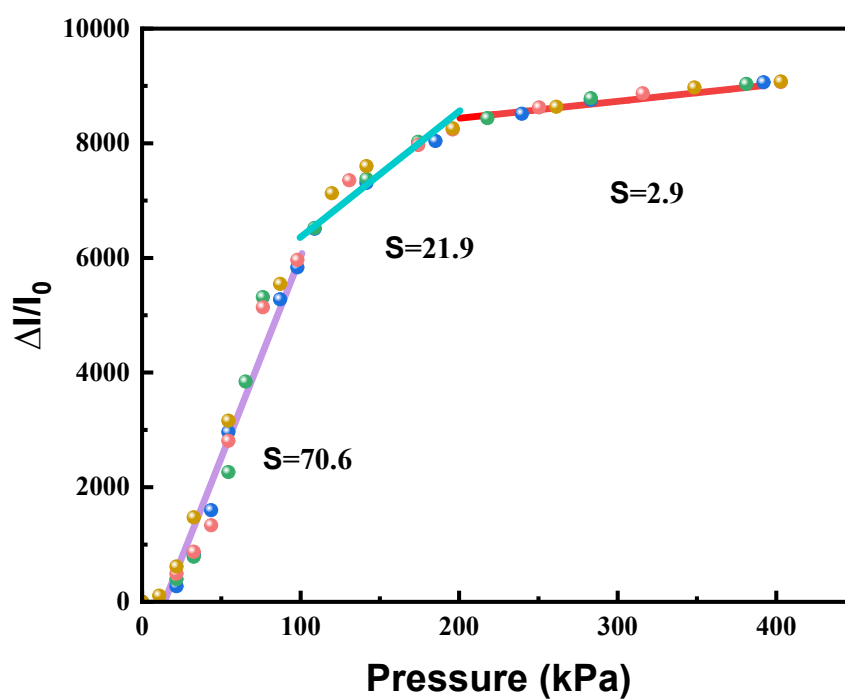


Figure S6 Response curve of MXene/PDMS piezoresistive sensor.

A	● —	J	● — — —	S	● ● ●
B	— ● ● ●	K	— ● —	T	—
C	— ● — ●	L	● — ● ●	U	● ● —
D	— ● ●	M	— —	V	● ● ● —
E	●	N	— ●	W	● — —
F	● ● — ●	O	— — —	X	— ● ● —
G	— — ●	P	● — — ●	Y	— ● — —
H	● ● ● ●	Q	— — ● —	Z	— — ●
I	● ●	R	● — ●		

Figure S7 International Morse code table.